

This set of VLSI Multiple Choice Questions & Answers (MCQs) focuses on “Basic MOS Transistors-1”.

1. Electronics are characterized by
a) low cost b) low weight and volume c) reliability d) all of the mentioned
Answer: d
Explanation: Electronics are characterized by reliability, low power dissipation, extremely low weight and volume, low cost, can cope up with high degree of sophistication and complexity.
2. Speed power product is measured as the product of
a) gate switching delay and gate power dissipation b) gate switching delay and gate power absorption c) gate switching delay and net gate power d) gate power dissipation and absorption
Answer: a
Explanation: Speed power product is measure in picojoules and it is the product of gate switching delay and gate power dissipation.
3. nMOS devices are formed in
a) p-type substrate of high doping level b) n-type substrate of low doping level c) p-type substrate of moderate doping level d) n-type substrate of high doping level
Answer: c
Explanation: nMOS devices are formed in a p-type substrate of moderate doping level. nMOS devices have higher mobility and is cheaper.
4. Source and drain in nMOS device are isolated by
a) a single diode b) two diodes c) three diodes d) four diode
Answer: b
Explanation: The source and drain regions are formed by diffusing n-type impurity, it gives rise to depletion region which extend in more lightly doped p-region. Thus Source and drain in a nMOS device are isolated by two diodes.
5. In depletion mode, source and drain are connected by
a) insulating channel b) conducting channel c) V_{dd} d) V_{ss}
Answer: b
Explanation: In depletion mode, source and drain are connected by conducting channel but the channel can be closed by applying suitable negative voltage to the gate.
6. The condition for non saturated region is
a) $V_{ds} = V_{gs} - V_t$ b) V_{gs} lesser than V_t c) V_{ds} lesser than $V_{gs} - V_t$ d) V_{ds} greater than $V_{gs} - V_t$
Answer: c
Explanation: The condition for non saturated region is V_{ds} lesser $V_{gs} - V_t$. In non saturation region MOSFET acts as voltage source. Varying V_{ds} will provide significant change in drain current.
7. In enhancement mode, device is in _____ condition
a) conducting b) non conducting c) partially conducting d) insulating
Answer: b
Explanation: In enhancement mode, the device is in non conducting condition. For n-type FET, threshold voltage is positive and p-type threshold voltage is negative.

8. The condition for non conducting mode is
a) V_{ds} lesser than V_{gs} b) V_{gs} lesser than V_{ds} c) $V_{gs} = V_{ds} = 0$ d) $V_{gs} = V_{ds} = V_s = 0$

Answer: d

Explanation: In enhancement mode the device is in non conducting mode, and its condition is $V_{ds} = V_{gs} = V_s = 0$.

9. nMOS is
a) donor doped b) acceptor doped c) all of the mentioned d) none of the mentioned

Answer: b

Explanation: nMOS transistors are acceptor doped. Acceptor is a dopant which when added forms p-type region. Some of the acceptors are silicon, boron, aluminium etc.

10. MOS transistor structure is
a) symmetrical b) non symmetrical c) semi symmetrical d) pseudo symmetrical

Answer: a

Explanation: MOS transistor structure is completely symmetrical with respect to source and drain.

11. pMOS is
a) donor doped b) acceptor doped c) all of the mentioned d) none of the mentioned

Answer: a

Explanation: nMOS is acceptor doped and pMOS is donor doped devices. Acceptor doped forms p-type region and donor doped forms n-type region.

12. Inversion layer in enhancement mode consists of excess of
a) positive carriers b) negative carriers c) both in equal quantity d) neutral carriers

Answer: b

Explanation: Inversion layer in enhancement mode consists of excess of negative carriers that is electron.

13. The condition for linear region is
a) V_{gs} lesser than V_t b) V_{gs} greater than V_t c) V_{ds} lesser than V_{gs} d) V_{ds} greater than V_{gs}

Answer: b

Explanation: The condition for linear region is $V_{gs} > V_t$. The power of MOS in linear region is less. It is a power dissipating region.

14. As source drain voltage increases, channel depth
a) increases b) decreases c) logarithmically increases d) exponentially increases

15. Answer: b

Explanation: As source drain voltage V_{ds} increases, the channel depth at the drain end decreases.

16. MOS transistors consists of
a) semiconductor layer b) metal layer c) layer of silicon-di-oxide d) all of the mentioned

Answer: d

Explanation: MOS transistors is formed as a sandwich consisting of a semiconductor layer, a silicon-di-oxide layer and a metal layer.

17. In MOS transistors, _____ is used for their gate
a) metal b) silicon-di-oxide c) polysilicon d) gallium

Answer: c

Explanation: In MOS transistors, polycrystalline silicon is used for their gate region instead of metal. Polysilicon gates have replaced all other older devices.

18. The gate region consists of

- a) insulating layer b) conducting layer c) lower metal layer d) p type layer

Answer: b

Explanation: The gate region is a sandwich consisting of semiconductor layer, an insulating layer and an upper metal layer.

19. Electrical charge flows from

- a) source to drain b) drain to source c) source to ground d) source to gate

Answer: a

Explanation: Electrical charge or current flows from source to drain depending on the charge applied to the gate region.

20. Source in MOS transistors is doped with _____ material

- a) n-type b) p-type c) n & p type d) none of the mentioned

21. Answer: a

Explanation: Source and drain in the MOS transistors are doped with N-type material and substrate is doped with p-type material.

22. In N channel MOSFET which is the more negative of the elements?

- a) source b) gate c) drain d) source and drain

Answer: a

Explanation: In N channel MOSFET, source is the more negative of the elements and in the case of P channel MOSFET, it is the more positive of the elements.

23. If the gate is given sufficiently large charge, electrons will be attracted to

- a) drain region b) channel region c) switch region d) bulk region

Answer: b

Explanation: If the gate is given sufficiently large charge, the negative charge carriers, electrons will be attracted from the bulk of the substrate material into the channel region below the oxide.

24. Enhancement mode device acts as _____ switch, depletion mode acts as _____ switch

- a) open, closed b) closed, open c) open, open d) close, close

Answer: a

Explanation: Enhancement mode transistor acts as open switch whereas depletion mode transistor acts as normally closed switch.

25. Depletion mode MOSFETs are more commonly used as

- a) switches b) resistors c) buffers d) capacitors

Answer: b

Explanation: Depletion mode MOSFETs are more commonly used as resistors than as switches. As permanently on switch it has high resistance.

26. Enhancement mode MOSFETs are more commonly used as

- a) switches b) resistors c) buffers d) capacitor

Answer: a

Explanation: Enhancement mode MOSFETs are more commonly used as switches and depletion mode devices are more used as resistors.

27. Depletion mode transistor should be large.

- a) true b) false

Answer: a

Explanation: Depletion mode transistors should be made large that is long and thin to create the large 'on' resistance.

28. Which expression is true?

- a) charging time < discharging time b) charging time > discharging time c) charging time = discharging time d) charging time and discharging time are not related

Answer: b

Explanation: When driving a capacitive output load, charging time will be long compared to the discharging time.

29. Overheating in device occurs due to less number of resistors per unit area.

- a) true b) false

Answer: b

Explanation: When the number of resistors per unit area increases, the device may not dissipate heat very well. This results in device overheating which leads to its failure.

30. In n channel MOSFET, _____ is constant

- a) channel length b) channel width c) channel depth d) channel concentration

Answer: a

Explanation: In all n channel MOSFET transistors, channel length is constant where as channel width can be varied.

31. VLSI technology uses _____ to form integrated circuit

- a) transistors b) switches c) diodes d) buffers

Answer: a

Explanation: Very-large scale integration is the process of creating integrated circuit with thousands of transistors into one single chip.

32. Medium scale integration has

- a) ten logic gates b) fifty logic gates c) hundred logic gates d) thousands logic gates

Answer: c

Explanation: Small scale integration has one or more logic gate. Further improved technology is medium scale integration which consists of hundred logic gates. Large scale integration has thousand logic gates.

33. The difficulty in achieving high doping concentration leads to

- a) error in concentration b) error in variation c) error in doping d) distribution error

Answer: b

Explanation: As photolithography comes closer to fundamental law of optics, achieving high accuracy in doping concentration becomes difficult, which leads to error due to variation.

34. _____ is used to deal with effect of variation

- a) chip level technique b) logic level technique c) switch level technique d) system level technique

Answer: d

Explanation: Designers must simulate multiple fabrication process or use system level technique for dealing with effects of variation.

35. As die size shrinks, the complexity of making the photomasks

- a) increases b) decreases c) remains the same d) cannot be determined

Answer: a

Explanation: As the die size shrinks due to scaling, the number of die per wafer increases and the complexity of making the photomasks increases rapidly.

36. _____ architecture is used to design VLSI

- a) system on a device b) single open circuit c) system on a chip d) system on a circuit

Answer: c

Explanation: SoC that is system on a chip architecture is used to design the very high level integrated circuit.

37. The design flow of VLSI system is

1. architecture design 2. market requirement 3. logic design 4. HDL coding

a) 2-1-3-4 b) 4-1-3-2 c) 3-2-1-4 d) 1-2-3-4

Answer: a

Explanation: The order of the design flow of VLSI circuit is market requirement, architecture design, logic design, HDL coding and then verification.

38. _____ is used in logic design of VLSI

a) LIFO b) FIFO c) FILO d) LILO

Answer: b

Explanation: First in first out (FIFO) technique and finite state machine technique is used in the logic design of the VLSI circuits.

39. Which provides higher integration density?

a) switch transistor logic b) transistor buffer logic c) transistor transistor logic d) circuit level logic

Answer: c

Explanation: Transistor-transistor logic offers higher integration density and it became the first integrated circuit revolution.

40. Physical and electrical specification is given in

a) architectural design b) logic design c) system design d) functional design

Answer: d

Explanation: Functional design defines the major functional units of the system, interconnections, physical and electrical specifications.

41. Which is the high level representation of VLSI design

a) problem statement b) logic design c) HDL program d) functional design

Answer: a

Explanation: Problem statement is a high level representation of the system. Performance, functionality and physical dimensions are considered here.

42. Gate minimization technique is used to simplify the logic.

a) true b) false

Answer: a

Explanation: Gate minimization technique is used to find the simplest, smallest and effective implementation of the logic.

43. VLSI technology uses _____ to form integrated circuit

a) transistors b) switches c) diodes d) buffers

Answer: a

Explanation: Very-large scale integration is the process of creating integrated circuit with thousands of transistors into one single chip.

44. Medium scale integration has

a) ten logic gates b) fifty logic gates c) hundred logic gates d) thousands logic gates

Answer: c

Explanation: Small scale integration has one or more logic gate. Further improved technology is medium scale integration which consists of hundred logic gates. Large scale integration has thousand logic gates.

45. The difficulty in achieving high doping concentration leads to
 a) error in concentration b) error in variation c) error in doping d) distribution error
 Answer: b
 Explanation: As photolithography comes closer to fundamental law of optics, achieving high accuracy in doping concentration becomes difficult, which leads to error due to variation.
46. _____ is used to deal with effect of variation
 a) chip level technique b) logic level technique c) switch level technique d) system level technique
 Answer: d
 Explanation: Designers must simulate multiple fabrication process or use system level technique for dealing with effects of variation.
47. As die size shrinks, the complexity of making the photomasks
 a) increases b) decreases c) remains the same d) cannot be determined
 Answer: a
 Explanation: As the die size shrinks due to scaling, the number of die per wafer increases and the complexity of making the photomasks increases rapidly.
48. _____ architecture is used to design VLSI
 a) system on a device b) single open circuit c) system on a chip d) system on a circuit
 Answer: c
 Explanation: SoC that is system on a chip architecture is used to design the very high level integrated circuit.
49. The design flow of VLSI system is
 1. architecture design 2. market requirement 3. logic design 4. HDL coding
 a) 2-1-3-4 b) 4-1-3-2 c) 3-2-1-4 d) 1-2-3-4
 Answer: a
 Explanation: The order of the design flow of VLSI circuit is market requirement, architecture design, logic design, HDL coding and then verification.
50. _____ is used in logic design of VLSI
 a) LIFO b) FIFO c) FILO d) LILO
 Answer: b
 Explanation: First in first out (FIFO) technique and finite state machine technique is used in the logic design of the VLSI circuits.
51. Which provides higher integration density?
 a) switch transistor logic b) transistor buffer logic c) transistor transistor logic d) circuit level logic
 Answer: c
 Explanation: Transistor-transistor logic offers higher integration density and it became the first integrated circuit revolution.
52. Physical and electrical specification is given in
 a) architectural design b) logic design c) system design d) functional design
 Answer: d
 Explanation: Functional design defines the major functional units of the system, interconnections, physical and electrical specifications.
53. Which is the high level representation of VLSI design
 a) problem statement b) logic design c) HDL program d) functional design

Answer: a

Explanation: Problem statement is a high level representation of the system. Performance, functionality and physical dimensions are considered here.

54. Gate minimization technique is used to simplify the logic.

a) true b) false

Answer: a

Explanation: Gate minimization technique is used to find the simplest, smallest and effective implementation of the logic.

55. nMOS fabrication process is carried out in

a) thin wafer of a single crystal b) thin wafer of multiple crystals c) thick wafer of a single crystal d) thick wafer of multiple crystals

Answer: a

Explanation: nMOS fabrication process is carried out in thin wafer of a single crystal with high purity.

56. _____ impurities are added to the wafer of the crystal

a) n impurities b) p impurities c) silicon d) crystal

Answer: b

Explanation: p impurities are introduced as the crystal is grown. This increases the hole concentration in the device.

57. What kind of substrate is provided above the barrier to dopants?

a) insulating b) conducting c) silicon d) semi conducting

Answer: a

Explanation: Above a layer of silicon dioxide which acts as barrier, insulating layer is provided upon which other layers may be deposited and patterned.

58. The photoresist layer is exposed to

a) visible light b) ultraviolet light c) infra red light d) LED

Answer: b

Explanation: The photoresist layer is exposed to ultraviolet light to mark the regions where diffusion is to take place.

59. In nMOS device, gate material could be

a) silicon b) polysilicon c) boron d) phosphorus

Answer: b

Explanation: In nMOS device, the gate material could be metal or polysilicon. This polysilicon layer has heavily doped polysilicon deposited by CVD.

60. The commonly used bulk substrate in nMOS fabrication is

a) silicon crystal b) silicon-on-sapphire c) phosphorus d) silicon-di-oxide

Answer: c

Explanation: In nMOS fabrication, the bulk substrate used can be either bulk silicon or silicon-on-sapphire.

61. In nMOS fabrication, etching is done using

a) plasma b) hydrochloric acid c) sulphuric acid d) sodium chloride

Answer: a

Explanation: In nMOS fabrication, etching is done using hydrofluoric acid or plasma. Etching is a process used to remove layers from the surface.

62. Heavily doped polysilicon is deposited using

- a) chemical vapour decomposition
- b) chemical vapour deposition
- c) chemical deposition
- d) dry deposition

Answer: b

Explanation: The polysilicon layer consists of heavily doped polysilicon deposited by chemical vapour deposition.

Propagation Delays”.

1. Propagation time is directly proportional to

- a) x
- b) $1/x$
- c) x^2
- d) $1/x^2$

View Answer

Answer: c

Explanation: Propagation time is directly proportional to square of the propagation distance (x^2). It is the time taken by the signal to move from input port to output port.

2. The total resistance can be given as

- a) nR_s
- b) nrR_s
- c) rR_s
- d) R_s

View Answer

Answer: b

Explanation: The total resistance can be given as the product of nrR_s where r is the relative resistance per section in terms of R_s .

3. Total capacitance can be given as

- a) $n(\text{square } C_g)$
- b) $nc(\text{square } C_g)$
- c) $c(\text{square } C_g)$
- d) $\text{square } C_g$

View Answer

Answer: b

Explanation: Total capacitance can be given as the product of $nc(\text{square } C_g)$ where c is the relative capacitance per section in terms of $\text{square } C_g$.

4. Overall delay is directly proportional to

- a) n
- b) $1/n$
- c) n^2

d) $1/n^2$

[View Answer](#)

Answer: c

Explanation: The overall delay is directly proportional to n^2 , where n is the number of pass transistors in series.

5. The number of pass transistors connected in series can be increased if

- a) compressor is connected
- b) buffer is connected
- c) ground is connected
- d) voltage regulator is connected

[View Answer](#)

Answer: b

Explanation: The number of pass transistors connected in series can be increased by connecting buffer in between.

6. Buffer is used because

- a) it increases the speed
- b) decreases sensitivity to noise
- c) decreases speed
- d) does not affect speed

[View Answer](#)

Answer: a

Explanation: Buffer is used for long polysilicon runs because it increases the speed and reduces the sensitivity to noise.

7. The overall delay is _____ to the relative resistance r

- a) directly proportional
- b) inversely proportional
- c) exponentially proportional
- d) not dependent

[View Answer](#)

Answer: a

Explanation: The overall delay is directly proportional to the relative resistance r. Overall delay is given as product of $n^2rc\tau$.

8. Small disturbances of noise

- a) decreases the inverter voltage
- b) increases the output voltage
- c) switches the inverter stage between 0 to 1
- d) does not switch the stage and keeps it stable

[View Answer](#)

Answer: c

Explanation: Small disturbances of noise switches the inverter stage between 0 and 1 or vice versa. It disturbs the normal operation or behaviour.

9. The buffer speeds up the

- a) rise time
- b) fall time
- c) all of the mentioned
- d) none of the mentioned

View Answer

Answer: a

Explanation: The buffer speeds up the rise time of propagated signal edge. A buffer is the combination of two inverters in which one output is fed to the other as the input.

10. Overall delay increases as n

- a) increases
- b) decreases
- c) exponentially decreases
- d) logarithmically decreases

View Answer

Answer: a

Explanation: Overall delay increases as n increases where n is the number of pass transistors connected in series.

1. Which contribute to the wiring capacitance?

- a) fringing fields
- b) interlayer capacitance
- c) peripheral capacitance
- d) all of the mentioned

View Answer

Answer: d

Explanation: The sources of capacitances which contribute to the total wiring capacitance are fringing field capacitance, interlayer capacitance and peripheral capacitance.

2. What does the value d in fringing field capacitance measures?

- a) thickness of wire
- b) length of the wire
- c) wire to substrate separation
- d) wire to wire separation

View Answer

Answer: c

Explanation: The quantity d in fringing field capacitance measures the wire to substrate separation. It is the distance between the wire and the substrate used in the device.

3. Total wire capacitance is equal to

- a) area capacitance
- b) fringing field capacitance
- c) area capacitance + fringing field capacitance
- d) peripheral capacitance

View Answer

Answer: c

Explanation: Total wire capacitance can be given as the sum of area capacitance and fringing field capacitance.

4. Interlayer capacitance occurs due to

- a) separation between plates
- b) electric field between plates
- c) charges between plates
- d) parallel plate effect

View Answer

Answer: d

Explanation: Interlayer capacitance occurs due to parallel plate effect between one layer and another. When one capacitance value comes closer to another they create some combined effects.

5. Which capacitance must be higher?

- a) metal to polysilicon capacitance
- b) metal to substrate capacitance
- c) metal to metal capacitance
- d) diffusion capacitance

View Answer

Answer: a

Explanation: Metal to polysilicon capacitance should be higher than metal to substrate capacitance. This is due to that when one layer underlies the other and in consequence interlayer capacitance is highly dependent on layout.

6. Peripheral capacitance is given in _____ eper unit length

- a) nano farad
- b) pico farad
- c) micro farad
- d) farad

View Answer

Answer: b

Explanation: Peripheral capacitance is given in picofarads per unit length. This is the sidewall capacitance. Each diode has this side wall capacitance.

7. For greater relative value of peripheral capacitance, _____ should be small

- a) source area
- b) drain area
- c) both of the mentioned
- d) none of the mentioned

View Answer

Answer: c

Explanation: The smaller the source or drain area, the greater the relative value of peripheral capacitance as they are both inversely related.

8. Diffusion capacitance is equal to

- a) area capacitance
- b) peripheral capacitance
- c) fringing field capacitance
- d) area capacitance + peripheral capacitance

View Answer

Answer: d

Explanation: Diffusion capacitance is given by the sum of area capacitance and peripheral capacitance.

9. Polysilicon is suitable for

- a) small distance
- b) large distance
- c) all of the mentioned
- d) none of the mentioned

View Answer

Answer: a

Explanation: Polysilicon is unsuitable for routing Vdd or Vss other than for very small distance because of the relatively high R_s value of the polysilicon layer.

10. Which has high voltage drop?

- a) metal layer
- b) polysilicon layer
- c) diffusion layer
- d) silicide layer

View Answer

Answer: b

Explanation: Polysilicon layer has high voltage drop. It has moderate RC product.

11. Which layer has high capacitance value?

- a) metal
- b) diffusion
- c) silicide
- d) polysilicon

View Answer

Answer: b

Explanation: Diffusion or active layer has high capacitance value due to which it has low or moderate IR drop.

12. Which layer has high resistance value?

- a) polysilicon
- b) silicide
- c) diffusion
- d) metal

View Answer

Answer: a

Explanation: Polysilicon layer has high resistance value and due to this it has high IR drop.

13. While measuring the output load capacitance $C_{gs,n}$ and $C_{gs,p}$ is not considered. Why?

- a) Because $C_{gs,n}$ and $C_{gs,p}$ are the capacitances at the input nodes.
- b) Because $C_{gs,n}$ and $C_{gs,p}$ does not exist during the operation of CMOS inverter
- c) Because $C_{gs,n}$ and $C_{gs,p}$ are storing opposite charges and cancel out each other during calculation of load capacitance
- d) None of the mentioned

View Answer

Answer: a

Explanation: $C_{gs,n}$ and $C_{gs,p}$ are gate to source capacitances of nMOS and pMOS transistors in CMOS inverter. They are measured at input node. Therefore they are not considered for calculation of load capacitance.

14. During the calculation of load capacitance of a 1st stage CMOS inverter, the input node capacitances, $C_{gs,n}$ and $C_{gs,p}$ of the 2nd stage CMOS inverter is also considered.

- a) True
- b) False

View Answer

Answer: b

Explanation: Instead thin oxide capacitance over the gate area is used for calculation.

1. Conducting layer is separated from substrate using

- a) dielectric layer
- b) silicon layer

- c) metal layer
 - d) diffusion layer
- View Answer

Answer: a

Explanation: Conducting layer is separated from the substrate by using dielectric or insulating layer as both are electrical insulators that can be polarized by an applied electric field.

2. Gate to channel capacitance of 5 micron technology is _____ pF X $10^{(-4)}$ (micrometer)².

- a) 1
- b) 2
- c) 4
- d) 0.4

View Answer

Answer: c

Explanation: Gate to channel capacitance of 5 micron technology is 4 pF X $10^{(-4)}$ (micrometer)². It is the standard typical calculated value.

3. Area capacitance of diffusion region of 2 micron technology is _____ pF X $10^{(-4)}$ (micrometer)².

- a) 2
- b) 2.75
- c) 3.75
- d) 4.75

View Answer

Answer: c

Explanation: Area capacitance of diffusion region of 2 micron technology is 3.75 pF X $10^{(-4)}$ (micrometer)².

4. Relative capacitance of diffusion region of 5 micron technology is

- a) 1
- b) 0.25
- c) 1.25
- d) 2

View Answer

Answer: b

Explanation: The relative capacitance of diffusion region of 5 micron technology is 0.25. The relative value is calculated by comparing two values of same type.

5. A feature size square has

- a) $L > W$
- b) $W > L$
- c) $L = W$

d) $L > d$

[View Answer](#)

Answer: c

Explanation: A feature size square has $L = W$ and its gate to channel capacitance value is called as square C_g .

6. The standard square C_g value of a 5 micron technology is

a) 0.01 pF

b) 0.1 pF

c) 1 pF

d) 10 pF

[View Answer](#)

Answer: a

Explanation: The standard square C_g value of a 5 micron technology is 0.01 pF. This standard square C_g value can be calculated by using the area of standard square value and the capacitance value.

7. The standard square C_g value of a 1.2 micron technology is

a) 0.01 pF

b) 0.0023 pF

c) 0.023 pF

d) 0.23 pF

[View Answer](#)

Answer: b

Explanation: The standard square C_g value of a 1.2 micron technology is 0.0023 pF.

8. Relative area for $L = 20\lambda$ and $W = 3\lambda$ is

a) 10

b) 15

c) 1/15

d) 1/10

[View Answer](#)

Answer: b

Explanation: Relative area for $L = 20\lambda$ and $W = 3\lambda$ is $= (20\lambda \times 3\lambda) / (2\lambda \times 2\lambda) = 15$. Relative area has no unit as two quantities of same type have been used.

9. The value of gate capacitance is

a) 0.25 square C_g

b) 1 square C_g

c) 1.25 square C_g

d) 1.5 square C_g

[View Answer](#)

Answer: b

Explanation: The value of gate capacitance is one square C_g . This is the standard value.

10. Delay unit of 5 micron technology is

- a) 1 nsec
- b) 0.1 nsec
- c) 0.01 nsec
- d) 1 sec

[View Answer](#)

Answer: b

Explanation: Delay unit of 5 micron technology is 0.1 nsec.

11. Delay unit of 1.2 micron technology is

- a) 0.064 nsec
- b) 0.0064 nsec
- c) 0.046 nsec
- d) 0.0046 nsec

[View Answer](#)

Answer: c

Explanation: The delay unit of 1.2 micron technology is 0.046 nsec.

12. What is the transition point of an inverter?

- a) V_{dd}
- b) $0.5 V_{dd}$
- c) $0.25 V_{dd}$
- d) $2 V_{dd}$

[View Answer](#)

Answer: b

Explanation: The transition point of an inverter is $0.5 V_{dd}$. Transition point is the point where different phases of same substance can be obtained in equilibrium.

13. What is the desired or safe delay value for 5 micron technology?

- a) 0.3 nsec
- b) 0.5 nsec
- c) 0.1 nsec
- d) 0.2 nsec

[View Answer](#)

Answer: a

Explanation: The desired or safe delay value for 5 micron technology is 0.3 nsec.

1. I_{ds} depends on

- a) V_g

- b) V_{ds}
- c) V_{dd}
- d) V_{ss}

View Answer

Answer: b

Explanation: I_{ds} depends on both V_{gs} and V_{ds} . The charge induced is dependent on gate to source voltage V_{gs} also charge can be moved from source to drain under influence of electric field created by V_{ds} .

2. I_{ds} can be given by

- a) $Q_c \times T$
- b) Q_c / T
- c) T / Q_c
- d) $Q_c / 2T$

View Answer

Answer: b

Explanation: I_{ds} can be given as charge induced in the channel(Q_c) divided by transit time (T). I_{ds} is equivalent to $(-I_{sd})$.

3. Transit time can be given by

- a) L / v
- b) v / L
- c) $v \times L$
- d) $v \times d$

View Answer

Answer: a

Explanation: Transit time (T) can be given by length of channel(L) by velocity(v). Transit time is the time required for an electron to travel between two electrodes.

4. Velocity can be given as

- a) μ / V_{ds}
- b) μ / E_{ds}
- c) $\mu \times E_{ds}$
- d) E_{ds} / μ

View Answer

Answer: b

Explanation: Velocity can be given as the product of electron or hole mobility(μ) and electric field(E_{ds}). It gives the flow velocity which an electron attains due to electric field.

5. E_{ds} is given by

- a) V_{ds} / L
- b) L / V_{ds}

- c) $V_{ds} \times L$
 - d) V_{dd} / L
- View Answer

Answer: a

Explanation: Electric field(E_{ds}) can be given as the ratio of V_{ds} and L . E_{ds} is the electric field created from drain to source due to volta V_{ds} .

6. Mobility of proton or hole at room temperature is

- a) $650 \text{ cm}^2/\text{V sec}$
- b) $260 \text{ cm}^2/\text{V sec}$
- c) $240 \text{ cm}^2/\text{V sec}$
- d) $500 \text{ cm}^2/\text{V sec}$

View Answer

Answer: c

Explanation: The value of mobility of proton or hole at room temperature is $240 \text{ cm}^2/\text{V sec}$. This gives the measure of how fast an electron can move.

7. In resistive region

- a) V_{ds} greater than $(V_{gs} - V_t)$
- b) V_{ds} lesser than $(V_{gs} - V_t)$
- c) V_{gs} greater than $(V_{ds} - V_t)$
- d) V_{gs} lesser than $(V_{ds} - V_t)$

View Answer

Answer: b

Explanation: In non saturated or resistive region, V_{ds} lesser than $V_{gs} - V_t$ where V_{ds} is the voltage between drain and source, V_{gs} is the gate-source voltage and V_t is the threshold voltage.

8. The condition for saturation is

- a) $V_{gs} = V_{ds}$
- b) $V_{ds} = V_{gs} - V_t$
- c) $V_{gs} = V_{ds} - V_t$
- d) V_{ds} greater than $V_{gs} - V_t$

View Answer

Answer: b

Explanation: The condition for saturation is $V_{ds} = V_{gs} - V_t$, since at this point IR drop in the channel equals the effective gate to channel voltage at the drain.

9. Threshold voltage is negative for

- a) nMOS depletion
- b) nMOS enhancement
- c) pMOS depletion

d) pMOS enhancement

View Answer

Answer: a

Explanation: The threshold voltage for nMOS depletion denoted as V_{td} is negative.

10. The current I_{ds} _____ as V_{ds} increases

a) increases

b) decreases

c) remains fairly constant

d) exponentially increases

View Answer

Answer: c

Explanation: The current I_{ds} remains fairly constant as V_{ds} increases in the saturation region.

11. In linear region, _____ channel exists

a) uniform

b) non-uniform

c) wide

d) uniform and wide

View Answer

Answer: a

Explanation: In linear region of MOSFET, the channel is uniform and narrow. This is the concentration distribution.

12. When the channel pinches off?

a) $V_{gs} > V_{ds}$

b) $V_{ds} > V_{gs}$

c) $V_{ds} > (V_{gs} - V_{th})$

d) $V_{gs} > (V_{ds} - V_{th})$

View Answer

Answer: c

Explanation: In MOSFET, in saturation region, when $V_{ds} > (V_{gs} - V_{th})$, the channel pinches off that is the channel current at the drain spreads out.

13. When threshold voltage is more, leakage current will be

a) more

b) less

c) all of the mentioned

d) none of the mentioned

View Answer

Answer: b

Explanation: Increasing the threshold voltage, leads to small leakage current when turned off and reduces current flow when turned on.

14. MOSFET is used as

- a) current source
- b) voltage source
- c) buffer
- d) divider

[View Answer](#)

Answer: a

Explanation: MOSFET is used as current source. Bipolar junction transistor also acts as good current source.